



# Certificate of Presentation

We hereby certify that the work

**Proximity effect correction for artificial kagome spin ice fabrication**

by

**Breno M. Cecchi, Murilo F. Velo, Emilio C. Bortolucci, G. H. M. de Aguiar and Kleber Roberto Pirola**

was presented at the XIV Workshop on Semiconductors and Micro & Nano Technology, in Campinas-SP, held on April 11-12, 2019.

A handwritten signature in blue ink, appearing to read "Jacobus Swart", written over a horizontal line.

Dr. Jacobus Swart  
SEMINATEC 2019 General Chair